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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Katsuhiko MIYA

Date: June 2, 2005

Serial No.: 10/648,918

Group Art Unit: 1763

Filed: August 27, 2003

Examiner: Rudy ZERVIGON

For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE
PROCESSING METHOD DRYING SUBSTRATE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT
REMARKS/ARGUMENT

This Response is filed in reply to the Restriction Requirement mailed May 5, 2005. Applicant elects the invention of Group I: Claims 1-10, drawn to a substrate processing apparatus, classified in Class 156, subclass 345.17.

Applicant reserves the right to file a divisional application directed to the subject matter covered in the non-elected claims.

Early and favorable consideration of the present application is earnestly solicited.

If this communication is filed after the statutory time period had elapsed and no separate Petition is enclosed, the Commissioner for Patents is petitioned, under 37 C.F.R. §1.136(a), to extend the time for filing a response to the outstanding Office Action by the number of months which will avoid abandonment under 37 C.F.R. §1.135. The fee under 37 C.F.R. § 1.17 should be charged to our Deposit Account No. 15-0700.

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on June 2, 2005
Max Moskowitz

Name of applicant, assignee or
Registered Representative

Signature
June 2, 2005

Date of Signature

Respectfully submitted,

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